## Amendments to the Specification:

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At page 1, line 1, please substitute the following new title: -- WAFER PROBE STATION FOR LOW-CURRENT MEASUREMENTS - -

Please replace the paragraph beginning at page 1, line 3 with the following new paragraph:

-- This application is a continuation of U.S. Patent Application Ser. No. 10/274,086, filed October 17, 2002, which is a continuation of U.S. Patent Application Ser. No. 10/003,948, filed October 30, 2001, now U.S. Patent No. 6,492,822, which is a continuation of U.S. Patent Application Ser. No. 09/784,231, filed February 13, 2001, now U.S. Patent No. 6,335,628, which is a continuation of U.S. Patent Application Ser. No. 08/855,735, filed May 9, 1997, now U.S. Patent No. 6,232,788, which is a continuation of U.S. Patent Application Ser. No. 08/508,324 filed July 27, 1995, now U.S. Patent No. 5,663,653, which is a continuation of U.S. Patent Application Ser. No. 08/100,494, filed August 2, 1993, now U.S. Patent No. 5,457,398, which is a continuation in part of U.S. Patent Application Ser. No. 07/896,853 filed June 11, 1992, now U.S. Patent No. 5,345,170. U.S. Patent Application Ser. No. 08/508,325 filed on July 27, 1995 is also a continuation in part of U.S. Patent Application Ser. No. 08/417,982 filed on April 6, 1995, now U.S. Patent No. 5,532,609 which, in turn, is a divisional of U.S. Patent Application Ser. No. 08/245,581 filed May 18, 1994, now U.S. Patent No. 5,434,512, which is a divisional of U.S. Patent Application Ser. No. 07,896,853 filed on June 11, 1992, now U.S. Patent No. 5,345,170.--